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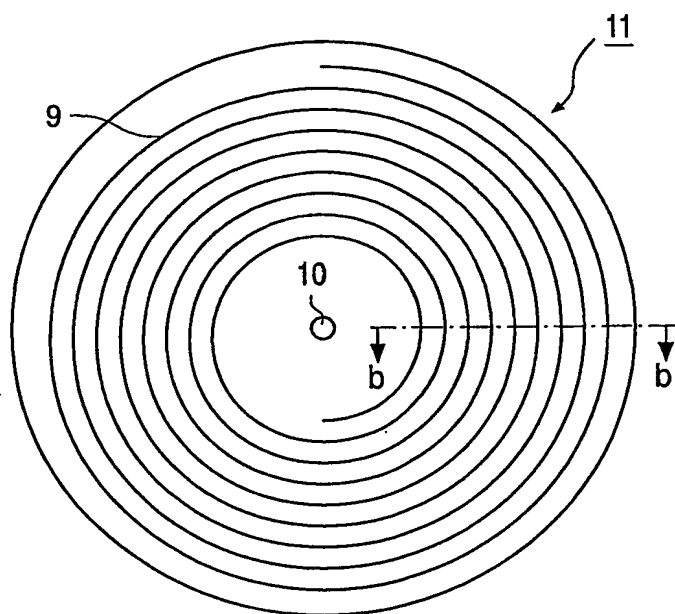


FIG. 1a

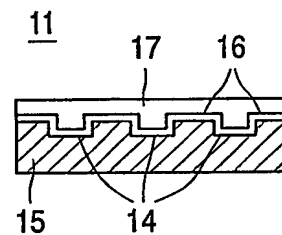


FIG. 1b

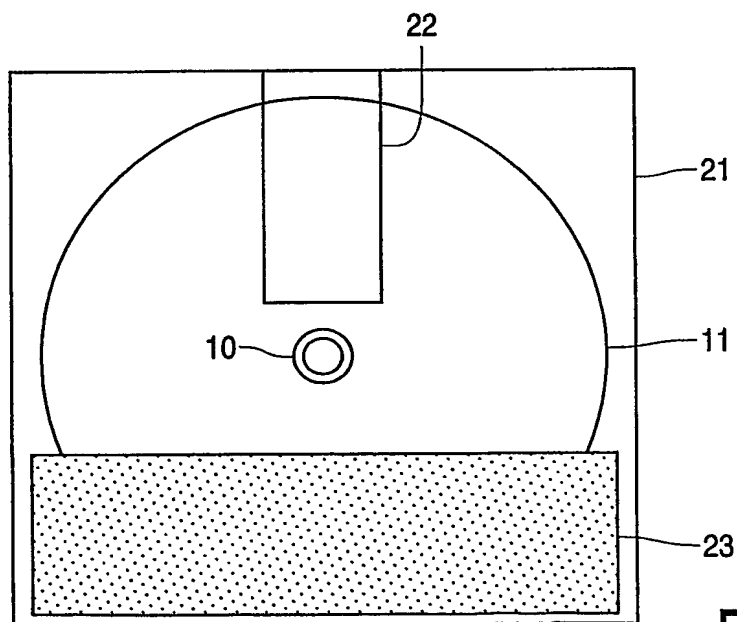


FIG. 2

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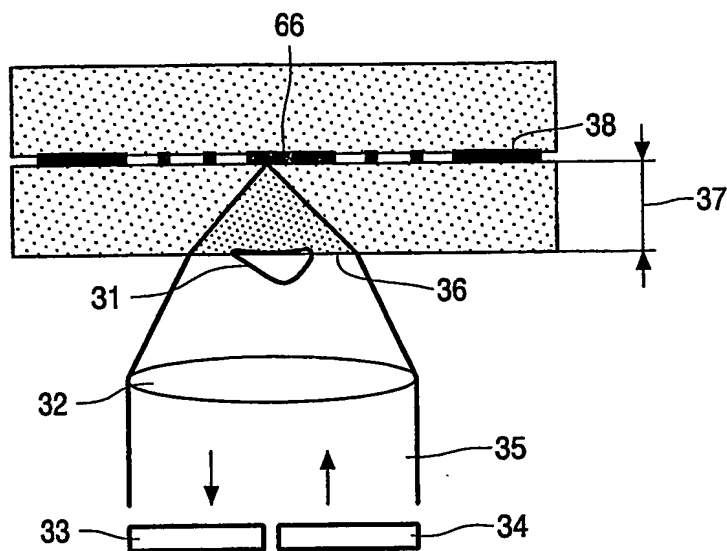


FIG. 3

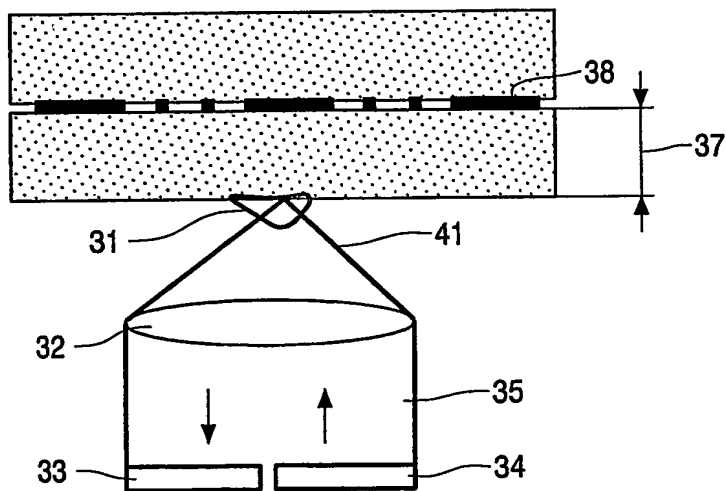


FIG. 4

A schematic diagram of a laser system for a lithographic apparatus. The system includes a laser source (52) with a beam splitter (59) and a lens (65). The laser beam is directed through a series of mirrors (50, 51, 53, 54) and a lens (66) to illuminate a substrate (1). The substrate is mounted on a stage (56) which is supported by a base (58). The diagram shows the optical path and the mechanical components of the system.

The schematic diagram illustrates a laser system for a lithographic apparatus. A laser beam (65) is emitted from a laser source (62) and focused through a lens (66) onto a substrate (1). The substrate is mounted on a stage (56) which is supported by a vertical column (55). The stage is connected to a base (58). The laser beam is controlled by a series of mirrors and lenses (50, 51, 52, 53, 54, 57, 58, 59, 60, 61, 63, 64). The beam path is shown as a series of connected lines with arrows indicating the direction of light flow. The diagram includes various components labeled with numbers: 1 (substrate), 50 (mirror), 51 (mirror), 52 (mirror), 53 (mirror), 54 (mirror), 55 (vertical column), 56 (stage), 57 (mirror), 58 (base), 59 (lens), 60 (mirror), 61 (mirror), 62 (laser source), 63 (mirror), 64 (output), 65 (laser beam), and 66 (lens).

FIG. 6